

Oral Presentation

[OLED2]OLED Material

Chair: Takahiro Komatsu (JOLED)

Co-Chair: Hitoshi Kuma (Idemitsu Kosan)

Wed. Nov 27, 2019 3:20 PM - 4:40 PM Room 204 (2F)

4:20 PM - 4:40 PM

[OLED2-4]Ellipsometry, XRR, and GCIB-TOF-SIMS Analysis of Small Molecule Layers in Solution Process and Vacuum Deposition Process

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Keywords:solution process, deposition process, organic light emitting diodes, time-of-flight secondary ion mass spectrometry, gas cluster ion beam

Ellipsometry, XRR, and GCIB-TOF-SIMS are applied to investigation of the spin-coating process as comparison of spin-coated samples and vacuum evaporated samples. The residual solvent of spin-coating process was observed in spin-coated samples by GCIB-TOF-SIMS. The result suggested that it can cause the decrease of refractive index observed in ellipsometry.